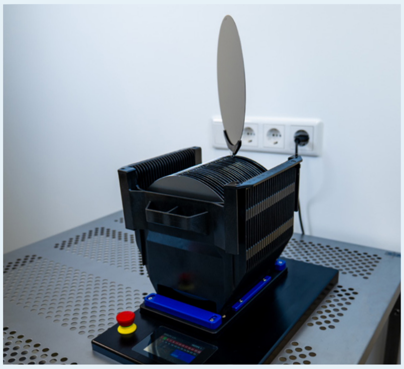
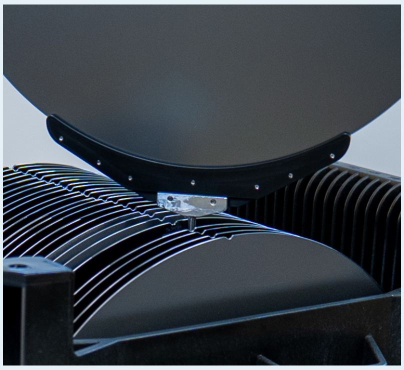
AUTOMATIC WAFER PRESENTER WITH ROTATION

The WHS-P1 is an automated single wafer presenter with rotation, engineered for precision handling and inspection of semiconductor wafers. Available for 76 mm (3”), 100 mm (4”), 150 mm (6”), and 200 mm (8”) diameter wafers, the WHS-P1 system fully lifts a single wafer from its cassette, allowing operators to safely remove the wafer or perform detailed inspection. The system also features a 180° wafer flip function for backside inspection or processing.

Many utilize the WHS-P1 to flip or invert wafers within the same cassette, maintaining the original wafer slot orientation. This reorientation process takes only a couple of minutes per lot and can be executed with a separate program, improving operational flexibility while keeping the wafers properly positioned in their slots.





Constructed from antistatic materials, the WHS-P1 ensures optimal wafer protection by minimizing electrostatic discharge and physical damage. Its design meets ISO 3 cleanroom standards, making it suitable for sensitive semiconductor environments where contamination control is critical.

Applications include wafer inspection processes such as macro analysis of surfaces, scratch and defect detection, post-epitaxial inspection, and layer uniformity assessments. The automated lifting and rotation eliminate manual wafer manipulation, reducing the risk of scratches and handling errors.

The WHS-P1 is available with an optional cleanroom-grade stainless steel table, designed to mount the unit at the ideal ergonomic height for operators.

Manufactured in an ISO9001 certified facility and CE certified, the WHS-P1 is designed for long-term performance in cleanroom environments.

FEATURES AND ADVANTAGES

- Precision opener for RSP150 reticle SMIF pods
- Antistatic and abrasion-resistant materials for protection
- Integrated lid holder to prevent contamination during use
- Ergonomic design for left- or right-hand operation
- Compatible with SEMI E111 and E112 RSP150 pods

AUTOMATIC WAFER PRESENTER WITH ROTATION

ITEM	SPECIFICATIONS
Sizes	76, 100, 150, 200 mm
Materials, lift blade	Antistatic PEEK
Materials, stage	Anodized aluminum
Materials, guides	Antistatic Polyoxymethylene
Cleanliness	ISO 3 (Class 1 FS209E)
**** NOTE: Please specify cassette model number when ordering ****	

ORDERING INFORMATION

WHS-P1 - 301

CODE	MODEL	
	301	Automatic wafer presenter, 76 mm (3”)
	401	Automatic wafer presenter, 100 mm (4”)
	601	Automatic wafer presenter, 150 mm (6”)
	801	Automatic wafer presenter, 200 mm (8”)
	Table	Table for the automatic wafer presenter **(optional)**

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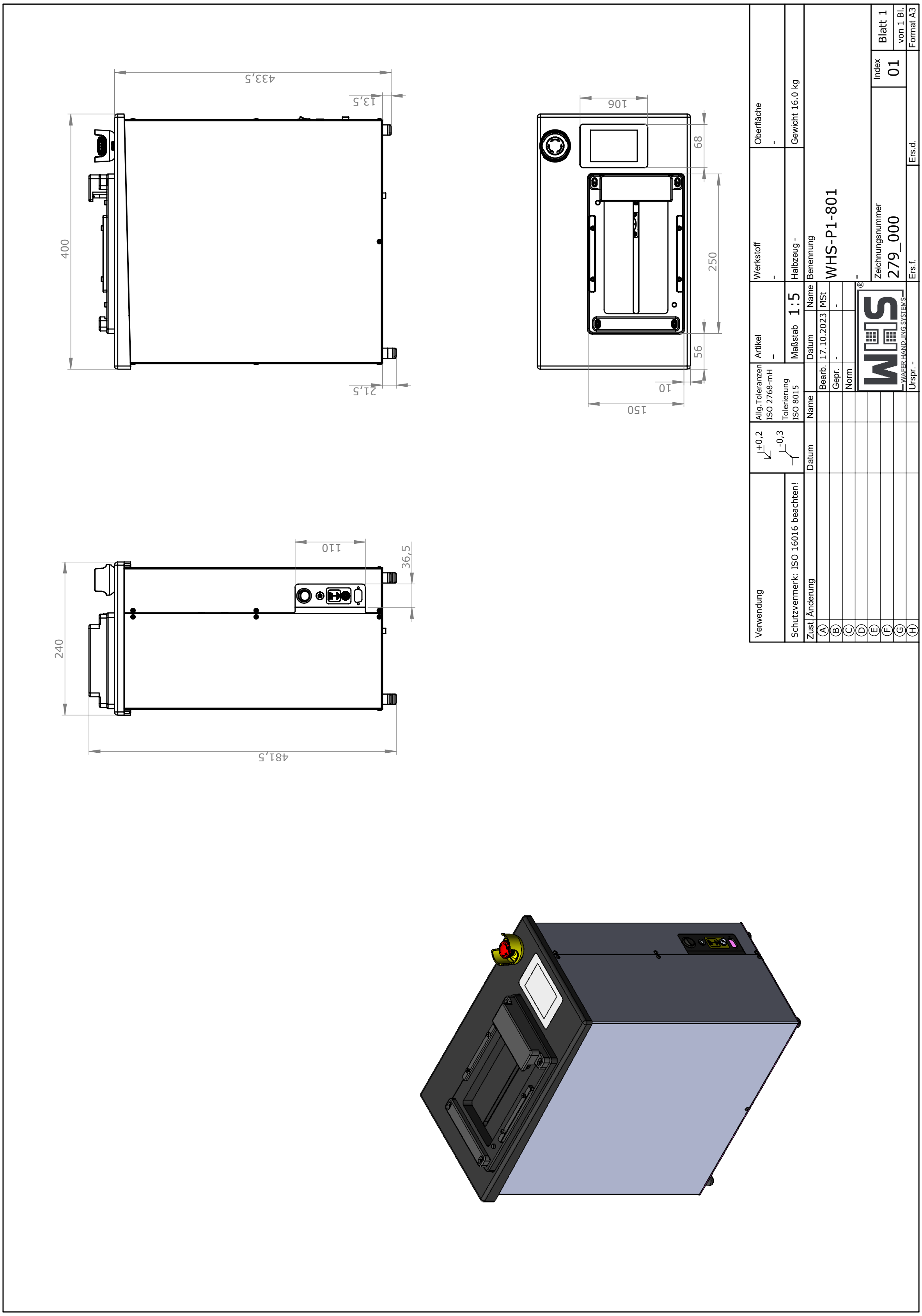
433,5
13,5
400
21,5
106
68
250
56
10
150
110
36,5
240
481,5
Verwendung
Schutzvermerk: ISO 16016 beachten!
+0,2
-0,3
Allg.Toleranzen ISO 2768-mH
Tolerierung ISO 8015
Artikel -
Maßstab 1:5
Werkstoff -
Halbzeug -
Oberfläche -
Gewicht 16.0 kg
Zust. Änderung
Datum
Name
A
B
C
D
E
F
G
H
Datum
Name
Bearb. 17.10.2023 MSt
Gepr. - -
Norm
Benennung
WHS-P1-801
-
WAFER HANDLING SYSTEMS
Urspr. -
Zeichnungsnummer
279_000
Ers.f.
Ers.d.
Index
01
Blatt 1
von 1 Bl.
Format A3

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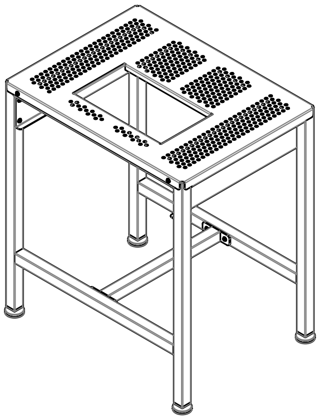

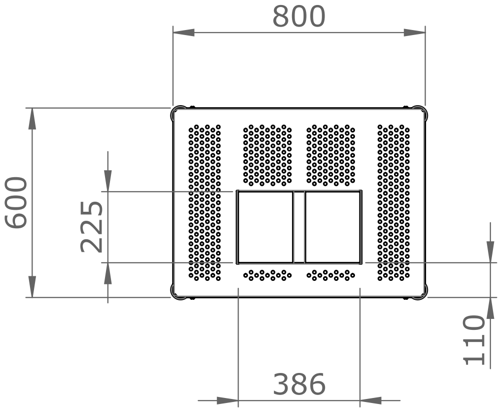

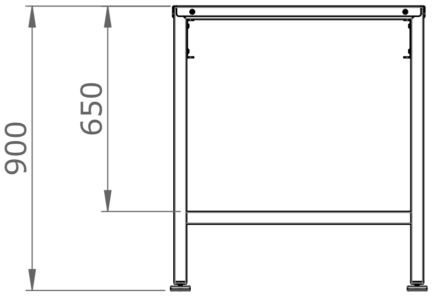

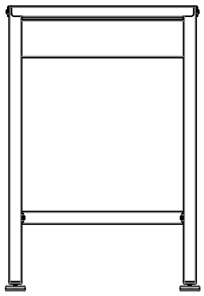

Materials:
Stainless Steel

WAFER HANDLING SYSTEMS.COM

WHS-P1-Table

Wafer Presenter Table

date: 19-01-2024 | scale: 1:20 | entity: mm | This drawing is owned by WHS trademark and may not be copied, reproduced or shown to third parties without written permission.